

- 3.2 Planar thick film element inspection. Inspection for visual defects described in this section shall be conducted on each planar thick film passive element. All inspection shall be performed at "low magnification" within the range of 10X to 60X magnification for both class H and class K.

Class HClass K

- 3.2.1 Operating metallization defects "low magnification". No element shall be acceptable that exhibits:

NOTE: The metallization defect criteria contained in this section apply to operating metallization only.

3.2.1.1 Metallization scratches

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- a. A scratch or probe mark in the metallization, excluding bonding pads, that both exposes underlying material anywhere along its length and leaves less than 50 percent of the original metallization width undisturbed (see figure 2032-38h).  
NOTE: Underlying material does not have to be exposed along the full length of the scratch.  
NOTE: This criteria does not apply to capacitors.

- a. Same as Class H.

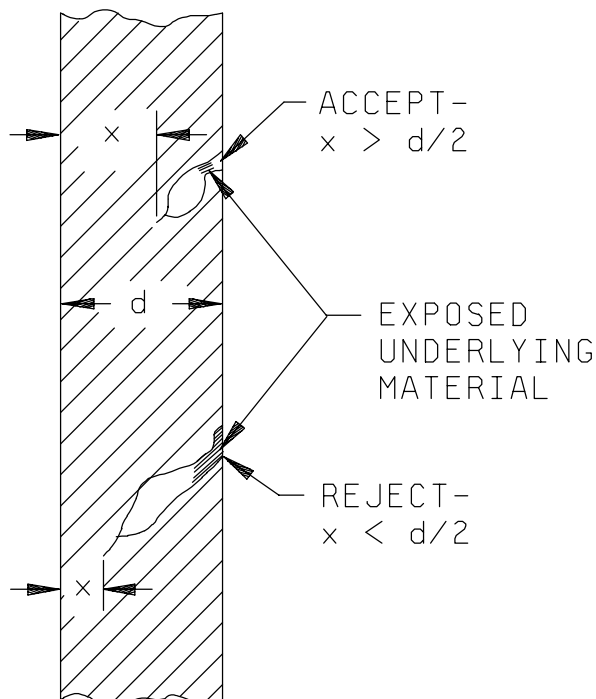


FIGURE 2032-38h. Class H metallization scratch criteria.